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5803
E. Hall



00862.022168

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Seiji TAKEUCHI et al.

Application No.: 09/819,670

Filed: March 29, 2001

For: STOCKER, EXPOSURE APPARATUS,
DEVICE MANUFACTURING METHOD,
SEMICONDUCTOR MANUFACTURING
FACTORY, AND EXPOSURE APPARATUS:
MAINTENANCE METHOD

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Examiner: A. Kosowski

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Group Art Unit: 2125

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May 6, 2003

RECEIVED

MAY 08 2003

Technology Center 2100

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT WITH PETITION FOR EXTENSION OF TIME AND
LETTER FORWARDING SUBSTITUTE SPECIFICATION

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Office Action dated January 6, 2003, for one month from April 6, 2003, up to and including May 6, 2003. A check in the amount of \$110.00 for payment of the extension fee is enclosed. Please charge any additional fee required for the extension, or credit any overpayment, to Deposit Account 06-1205.

In response to the Official Action dated January 6, 2003, please amend the above-

identified application as follows:

05/07/2003 NMOHAMM1 00000057 09819670

01 FC:1201 84.00 0P

05/07/2003 NMOHAMM1 00000057 09819670

02 FC:1251 110.00 0P

INTRODUCTORY COMMENTS

This Amendment has been prepared in accordance with the Revised Format established by the U.S. Patent and Trademark Office, as permitted in the Pre-OG Notice dated February 4, 2003, and entitled "Amendments in a Revised Format Now Permitted."